

10/058614

01/28/02

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U.S. UTILITY Patent Application

PATENT NUMBER and
ISSUE DATE

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10058614	01/28/2002	324	751	2002	NGUYEN, VINH P.

**APPLICANTS: Han Ligu; McCord Mark; 2829

**CONTINUING DATA VERIFIED:
THIS APPLN CLAIMS BENEFIT OF 60/341,348 12/17/2001

**FOREIGN APPLICATIONS VERIFIED:

<input checked="" type="checkbox"/> DO NOT PUBLISH		<input type="checkbox"/> RESCIND	ATTORNEY DOCKET NO. KLA1P058
Priority claimed	<input type="checkbox"/> yes <input type="checkbox"/> no		
35 USC 119 conditions met	<input type="checkbox"/> yes <input type="checkbox"/> no		
Verified and Acknowledged Examiner's initials			
TITLE: Multiple electron beam inspection system using uniform focus and deflection			

U.S. DEPT. OF COMM./PAT. & TM.-PT. 2 (3-10-01) 12-24

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.G.
Assistant Examiner		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg. Print Fig.
		Application Examiner	
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	
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